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ву:

Date: Septerby 11, 200

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant

: Alfred Kersch

Applic. No.

10/047,814

Filed

: January 15, 2002

Title

: Reaction Chamber for Processing a Substrate

Wafer, and Method for Operating the Chamber

Examiner

: William D. Coleman

Group Art Unit: 2823

AMENDMENT

Hon. Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Responsive to the Office action dated June 11, 2003 kindly amend the above-identified application as follows: